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**U.S. PATENT DOCUMENTS**

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date
AA						
AB						
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**FOREIGN PATENT DOCUMENTS**

Examiner Initial	Document Number	Date	Country	Class	Subclass	Abstract	
						Yes	No
AM	2001-23967	01/26/2001	JP	H01L	21/3065	X	
AN	2001-267299	09/28/2001	JP	H01L	21/3065	X	
AO							
AP							
AQ							
AR							
AS							
AT							

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

1763	AU	M.A. Lieberman, Translated by H. Sato, "Principles of Plasma Discharges and Materials Processing", Published November 20, 2001 by ED Research Co., Page 116
	AV	
	AW	
	AX	
	AY	
	AZ	
<b>Examiner</b> Prof. Zeng		<b>Date Considered</b> 10/2/06